

Amendment and Response Under 37 C.F.R. 1.116

Applicant: Craig K. Carlson-Stevermer

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Title: WAFER STAGING PLATFORM FOR A WAFER INSPECTION SYSTEM

IN THE SPECIFICATION

Please replace the paragraph beginning at page 4, line 2 with the following rewritten paragraph:

The handling system of the present invention is best shown in Figures 14-16. In accordance with one of the features of the invention, the handling system includes the novel and unique wafer staging platform 30 as shown best in Figures 14-15 that provides both a staging area or first platform 32 for a wafer waiting to be processed, and a temporary location or second platform 34 to place a processed wafer while the staged wafer is presented to the processing tool. The platforms 32, 34 can be arranged one above the other as shown in Figure 15. Figure 16 best illustrates the layout of the wafer handling system of the present invention with this wafer staging platform 30.